

# Developments towards a transversal electron target for CRYRING

Carsten Brandau, Alexander Borovik Jr., **Benjamin Ebinger**, Tobias Molkentin, Stefan Schippers, Alfred Müller



for the SPARC working group "Electron Targets", supported by BMBF



Bundesministerium für Bildung und Forschung

Justus-Liebig-University Giessen/GSI Darmstadt

19<sup>th</sup> of September 2016, SPARC Workshop, Kraków

### Outline

Concept and Physics Case

 Tests with a Multi-Electrode Target Optimized for the Giessen Low-Energy Single-Pass Setup

Status and Outlook

### Outline

Concept and Physics Case

 Tests with a Multi-Electrode Target Optimized for the Giessen Low-Energy Single-Pass Setup

Status and Outlook

#### Concept

**Transversal** target with electron beam formed like a **sheet/ribbon** 

De-lacceleration

Design parameters/goals: Electron-ion crossing angle =  $90^{\circ}$ Electron energy up to 10 keV Electron density up to  $10^{\circ}9 \text{ cm}^{-3}$ L = 6 - 10 cm

Ci Besting

Injection

Extraction

### **Physics Case**

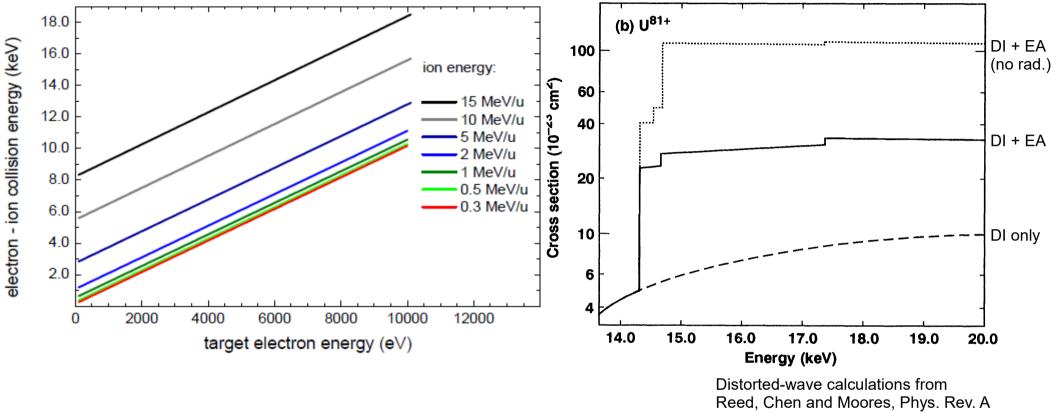
#### • Main advantages:

- Free electrons (no target nucleus)
  - $\rightarrow$  High energy resolution, no NRC, no excitations due to the nucleus
- Well localized interaction region
  - $\rightarrow$  Spectroscopy with large solid angles
- Easy and precise tunable collision energy

#### • Possible experiments:

- Photon spectroscopy (REC) at low ion energies
- Electron-impact excitation (EIE) and ionization (EII)
  - $\rightarrow$  Indirect and/or resonant contributions
- 2<sup>nd</sup> generation: Nuclear excitation by electron capture (NEEC) and resonant electron scattering (RES)

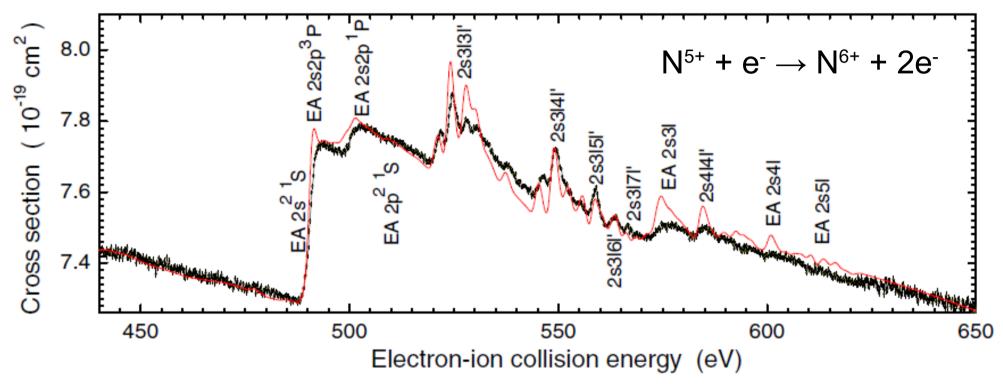
Physics Case Example: Ell of HCI



**44**, 4336 (1991)

- Investigation of heavy and highly charged ions, e.g. U<sup>81+</sup>
- Will importance of indirect processes (such as EA, log-scale for U<sup>81+</sup>) increase further?

#### Example From the Giessen Single-Pass Setup: EII of N<sup>5+</sup>



A. Müller et al., PRA 90 (2014) 010701(R).

- High-resolution cross section measurements with fine-step energy-scan method
- Measurement of accurate absolute cross sections (Giessen: ~ 6 %)

# Outline

Concept and Physics Case

 Tests with a Multi-Electrode Target Optimized for the Giessen Low-Energy Single-Pass Setup

Status and Outlook

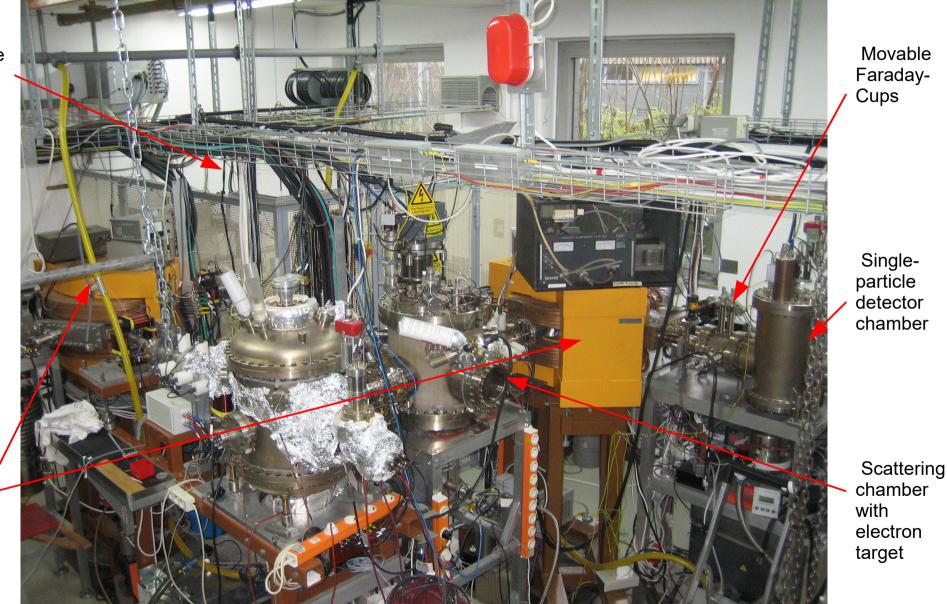
#### Giessen Low-Energy Single-Pass Setup

lon source in HVcage

Two

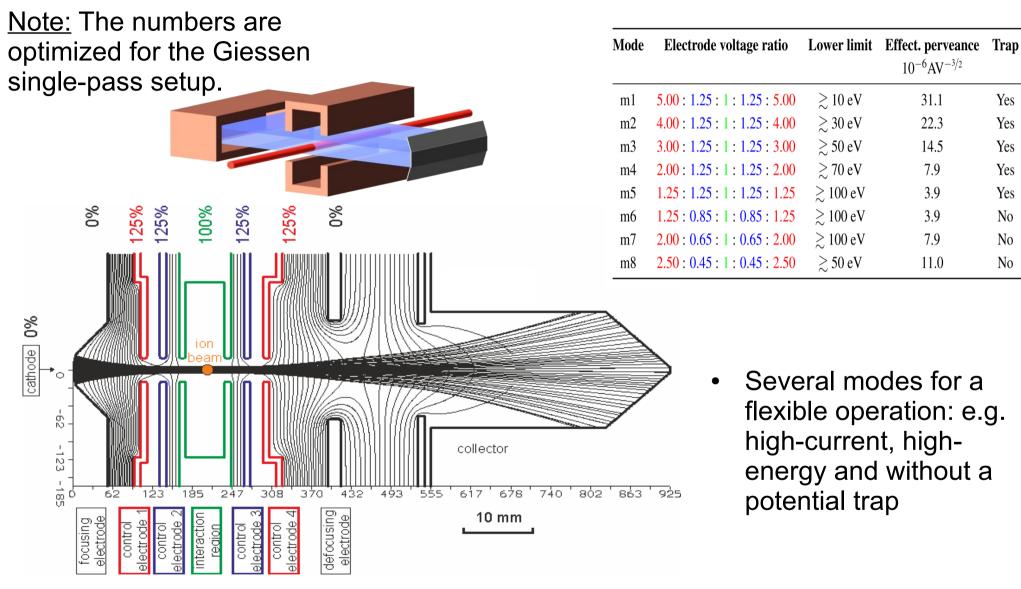
analyzing

magnets



9

#### Electron Target at Giessen



Successful operation of measurement principles at the Giessen single-pass setup since the 1980's

Yes

Yes

Yes

Yes

Yes

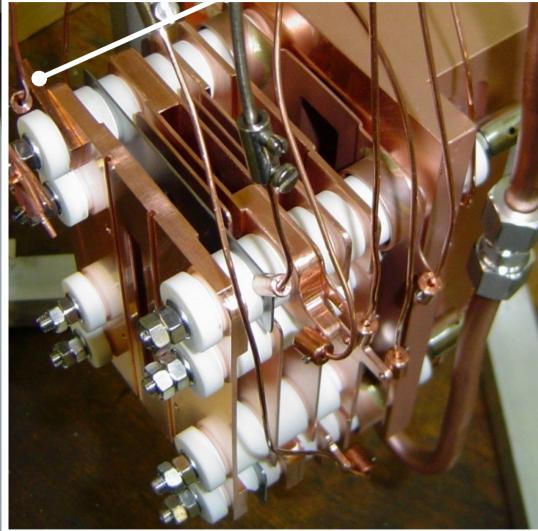
No

No

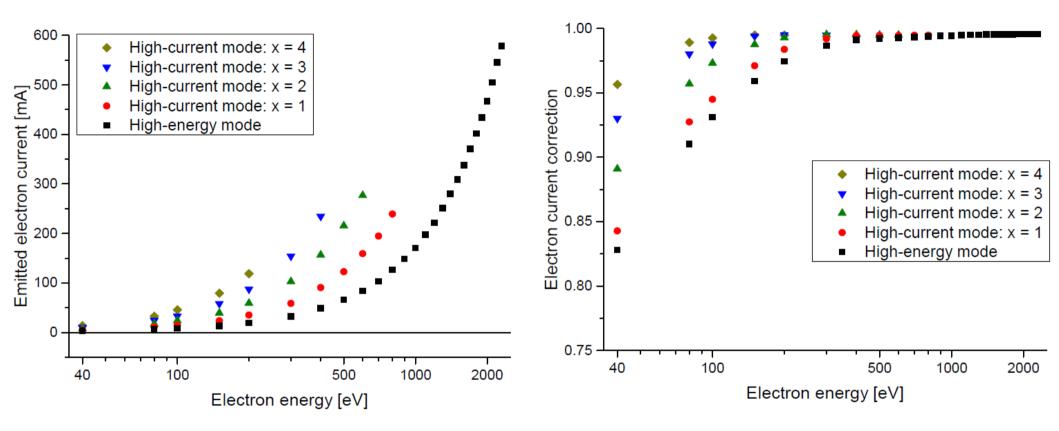
No

#### **Electron Target at Giessen**



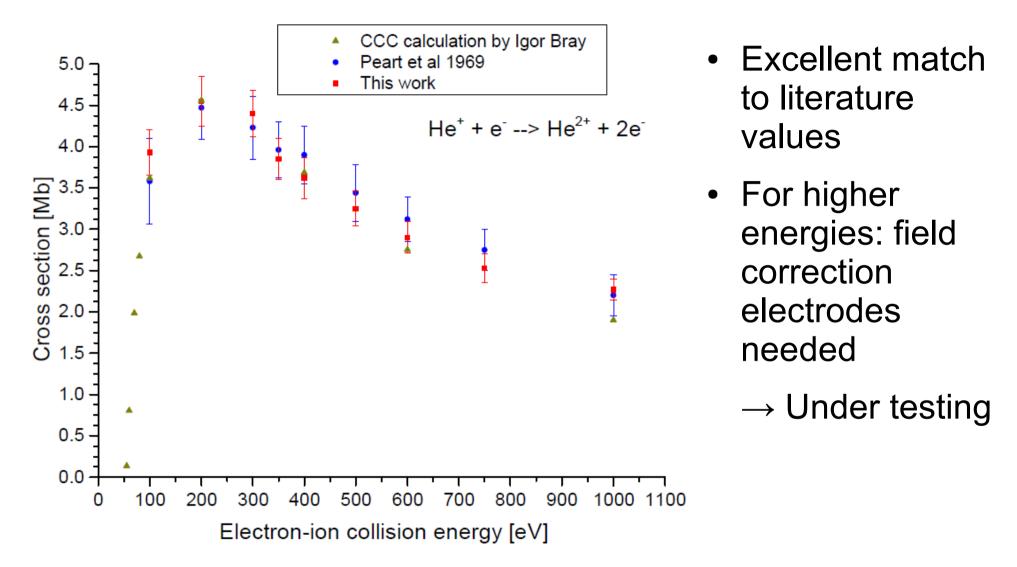


#### Tests at Giessen Single-Pass Setup



Different modes do work as expected

#### Tests at Giessen Single-Pass Setup



# Outline

Concept and Physics Case

 Tests with a Multi-Electrode Target Optimized for the Giessen Low-Energy Single-Pass Setup

Status and Outlook

#### Status

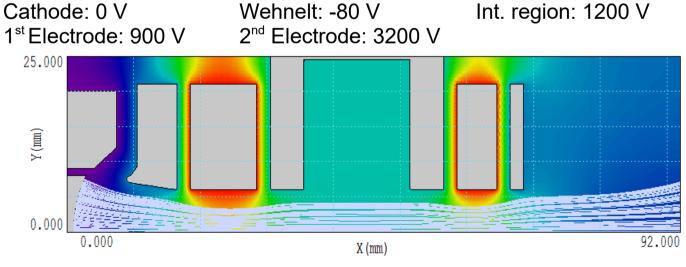
- Tasks towards a dedicated transversal target for CRYRING (ongoing work):
  - Improvement of the UHV capability (goal: few 10<sup>-11</sup> mbar)
  - Improvement of the high-voltage resistance
  - Larger aperture for ion beam
  - Improved collector design
  - Free view to interaction region (for spectroscopy)
    - $\rightarrow$  New electron optics calculations optimized for CRYRING
  - Storage ring integration (vacuum layout and mechanical design drafted)
  - Development of a new control and data acquisition system
    - $\rightarrow$  Working on integration into CRYRING/FAIR system

 Electron energy can be varied over a wide range (by a factor of 3) by changing just one parameter and still obtaining an acceptable beam quality

 $\rightarrow$  Well behaving electron beam, non-problematic handling

 Typically synchronous changing of voltages on all electrodes

Settings:



File: SHI WIDEGAP.TOU NPart: 75 Plot mode: XY Magnification: OFF Range: 1-75 NSkip: 1 Horiz. grid: 10.000 Vert. grid: 5.000 Filter 1: \_\_\_\_\_\_ Filter 2: \_\_\_\_\_\_ Filter 3: \_\_\_\_\_\_

File: SHI WIDEGAPP.EOU Plot type: Element Ouantity: Phi Minimum: -8.000E+01 3.200E+03 Maximum: 3.715E+01 2.714E+02 5.057E+02 7.400E+02 9.743E+02 1.209E+03 1.443E+03 1.677E+03 1.911E+03 2.146E+03 2.380E+03 2.614E+03 2.849E+03 3.083E+03

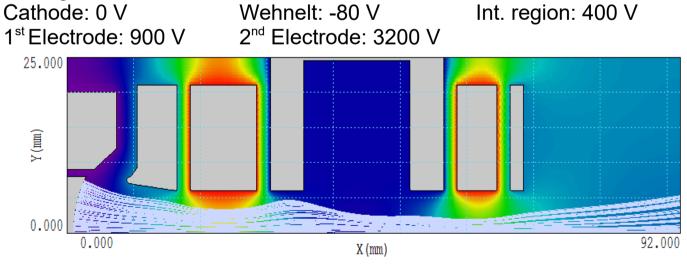


 Electron energy can be varied over a wide range (by a factor of 3) by changing just one parameter and still obtaining an acceptable beam quality

 $\rightarrow$  Well behaving electron beam, non-problematic handling

 Typically synchronous changing of voltages on all electrodes

Settings:



File: SHI WIDEGAP.TOU NPart: 75 Plot mode: XY Magnification: OFF Range: 1-75 NSkip: 1 Horiz. grid: 10.000 Vert. grid: 5.000 Filter 1: \_\_\_\_\_\_ Filter 2: \_\_\_\_\_\_ Filter 3: \_\_\_\_\_\_

File: SHI WIDEGAPP.EOU Plot type: Element Ouantity: Phi Minimum: -8.000E+01 3.200E+03 Maximum: 3.715E+01 2.714E+02 5.057E+02 7.400E+02 9.743E+02 1.209E+03 1.443E+03 1.677E+03 1.911E+03 2.146E+03 2.380E+03 2.614E+03 2.849E+03 3.083E+03

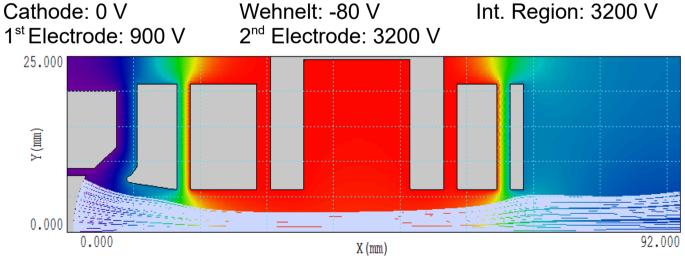


 Electron energy can be varied over a wide range (by a factor of 3) by changing just one parameter and still obtaining an acceptable beam quality

 $\rightarrow$  Well behaving electron beam, non-problematic handling

 Typically synchronous changing of voltages on all electrodes

Settings:



File: SHI WIDEGAP.TOU NPart: 75 Plot mode: XY Magnification: OFF Range: 1-75 NSkip: 1 Horiz. grid: 10.000 Vert. grid: 5.000 Filter 1: \_\_\_\_\_\_ Filter 2: \_\_\_\_\_\_ Filter 3: \_\_\_\_\_\_

File: SHI WIDEGAPP.EOU Plot type: Element Ouantity: Phi Minimum: -8.000E+01 3.200E+03 Maximum: 3.715E+01 2.714E+02 5.057E+02 7.400E+02 9.743E+02 1.209E+03 1.443E+03 1.677E+03 1.911E+03 2.146E+03 2.380E+03 2.614E+03 2.849E+03 3.083E+03

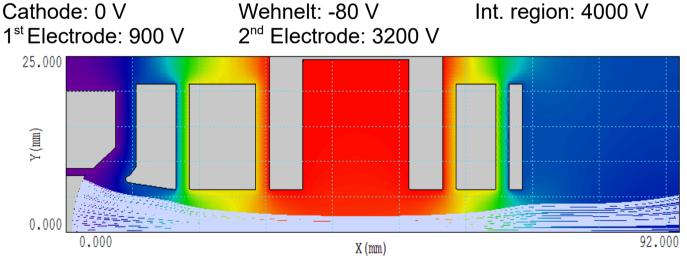


 Electron energy can be varied over a wide range (by a factor of 3) by changing just one parameter and still obtaining an acceptable beam quality

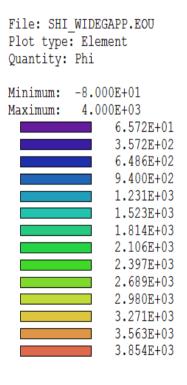
 $\rightarrow$  Well behaving electron beam, non-problematic handling

 Typically synchronous changing of voltages on all electrodes

Settings:



File: SHI WIDEGAP.TOU NPart: 75 Plot mode: XY Magnification: OFF Range: 1-75 NSkip: 1 Horiz. grid: 10.000 Vert. grid: 5.000 Filter 1: \_\_\_\_\_\_ Filter 2: \_\_\_\_\_\_ Filter 3: \_\_\_\_\_\_



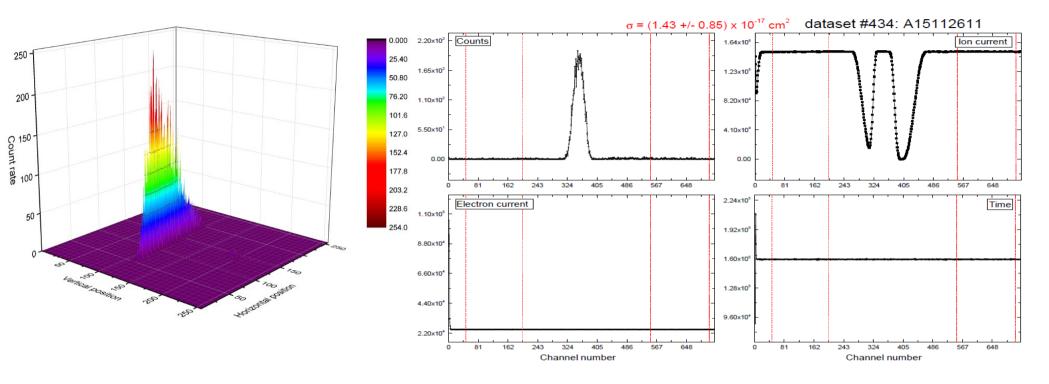


### Summary

- A transversal free-electron target dedicated for experiments at CRYRING is being developed
- Enables the investigation of a long list of electron-ion collision phenomena that were not accessible until now → see CRYRING Physics Book (in print) or Instrumentation TDR (http://www.fair-center.eu/fileadmin/fair/publications\_exp/TDR\_CRYRING\_Experimental\_Instrumentation.pdf)
- Test measurements with the Giessen electron target yield valuable information for the optimization of the CRYRING target
- Work on optimizations and modifications for the CRYRING target is in progress

# Thank you for your attention!

#### Tests at Giessen Single-Pass Setup

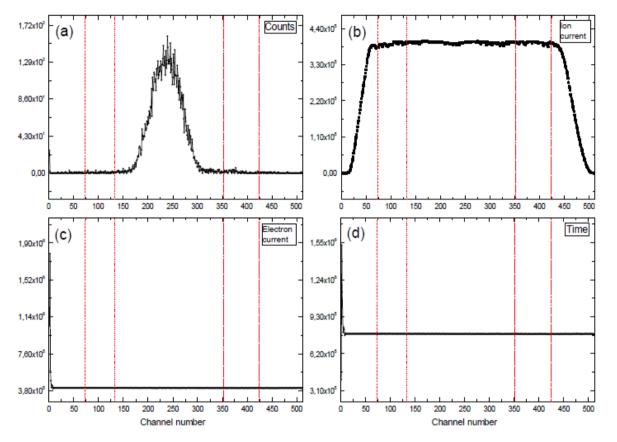


 Ion beam is influenced (deflected, splitted up) by electric field → Appropriate voltage settings on electrodes and field correction electrodes

#### Experimental Setup: Methods of Measurement

- Absolute measurements:
  - Deliver absolute ionization cross sections
  - To accurately know the quantity of the cross section
  - By sweeping the electron beam mechanically through the ion beam (animated crossed-beams)
- Relative measurements:
  - Deliver only relative cross section values
  - To accurately know the qualitative behavior of the cross section
  - By scanning the electron energy in very fine steps (fixed beam positions)
  - Can be fitted to absolute measurements

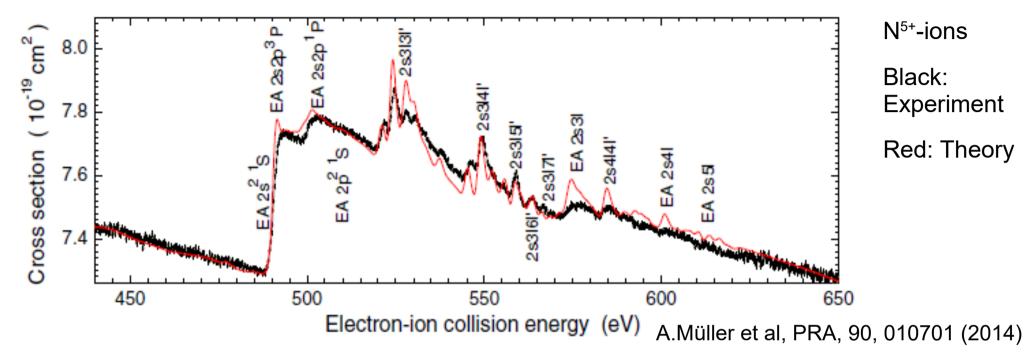
#### Exp. Setup: Absolute Measurements



- Systematic uncertainty can be brought down to about 6 %
- Typically steps of several up to 50 eV → No structures can be observed

- Not a trivial task at all
- Animated-beams make it a lot easier → Overlap and profile of beams get measured simultaneously with signal
- Still need to measure electron and ion current accurately as well as detect all product ions
  → Counting efficiency of detector

#### Exp. Setup: Scan Measurements



- Fine-steps of typically ~ 0.2 eV
- Ion and electron beam are fixed to the maximum overlap the entire time
- Low statistic uncertainty can be achieved in a short time as measurement is operated automatically
- Ionization threshold as well as positions of EA-thresholds and REDA/READIprocesses can be determined